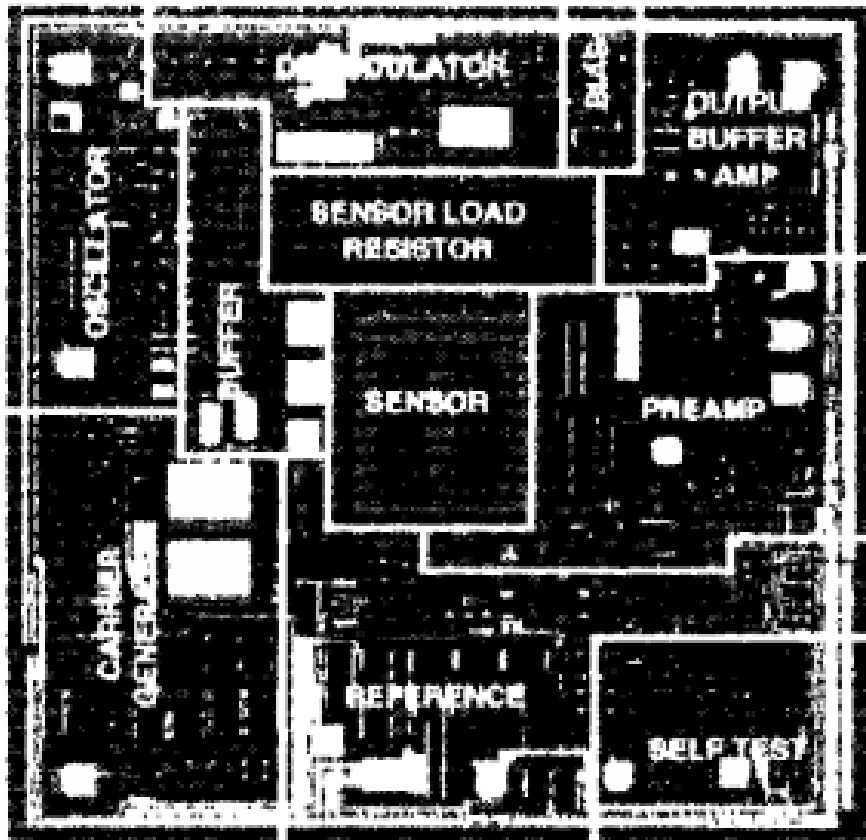
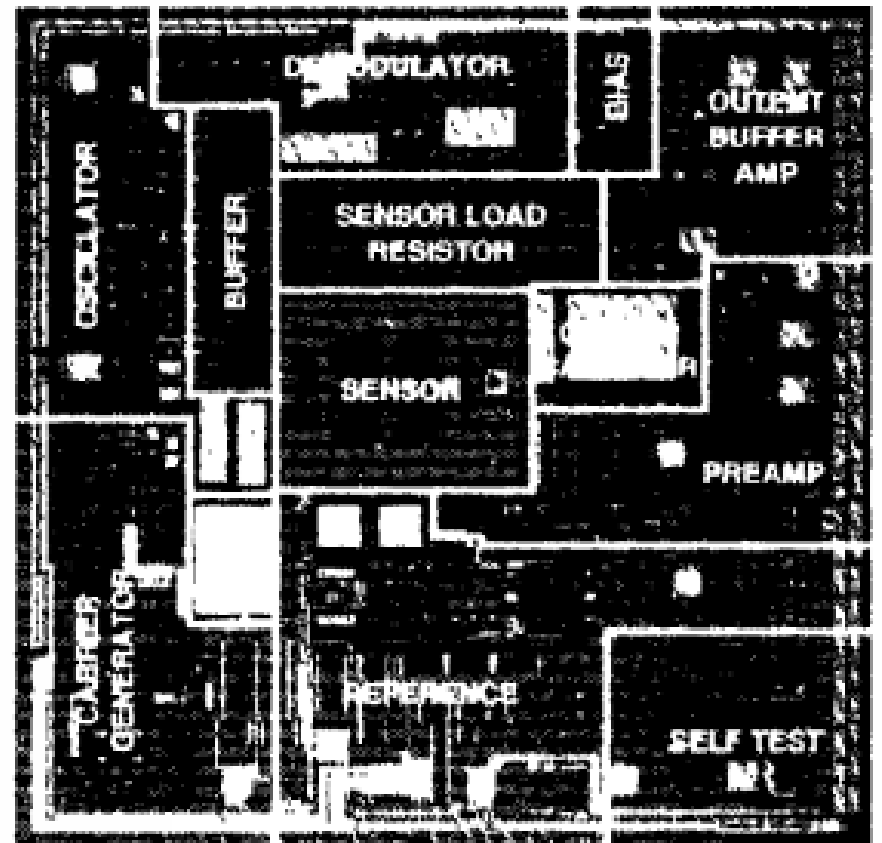


SURFACE MICROMACHINING

ISSCC 1995



ADXL05



ADXL50

Surface Micromachining: From Vision to Reality to Vision

IN 1995, PAYNE et al. (Analog Devices) described the opportunities of surface micromachining combined with on-chip bipolar/MOS electronics in integrated accelerometers. This approach continues to be commercially successful with now over 100 million integrated surface-micromachined accelerometers produced including integrated gyroscopes. This core enabling technology is also found in RF devices, micromechanical switches, and microactuators.

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